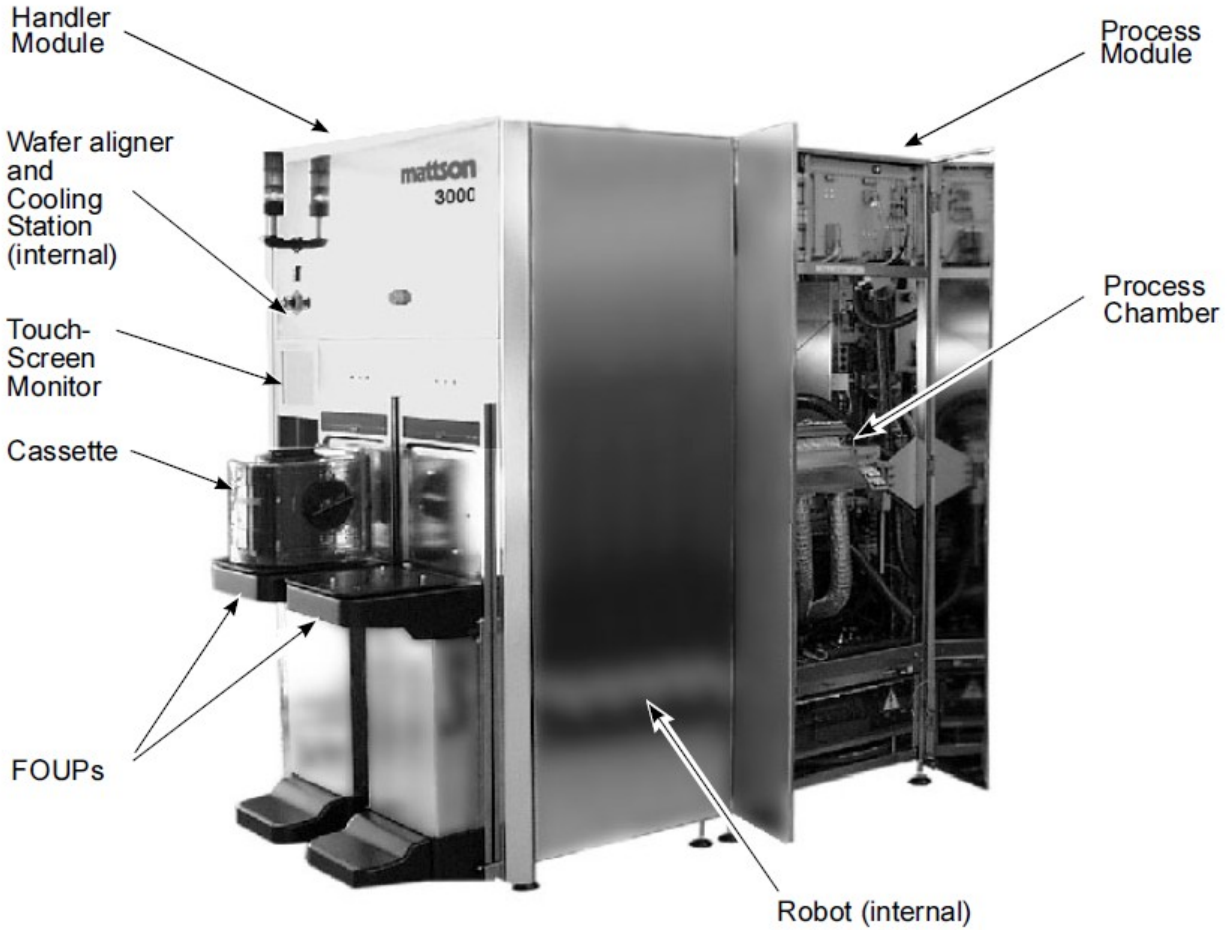


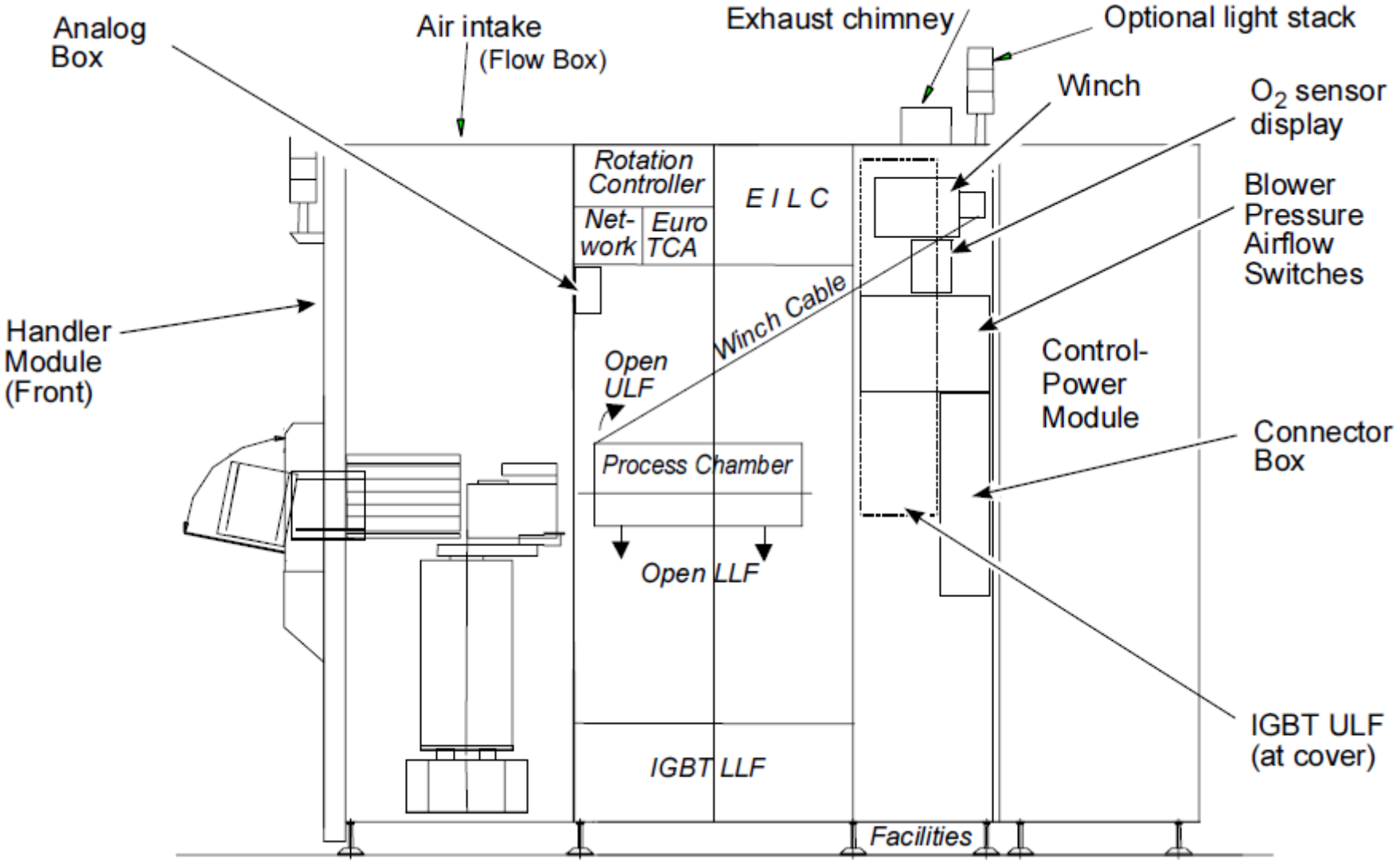
AST3000
Mattson

System Overview

The Mattson Technology 3000 is an advanced rapid thermal process (RTP) system capable of processing either 200mm or 300mm wafers. The system consists primarily of a process module (with process chamber), a wafer handler module and auxiliary equipment (e.g., control-power module, computer electronics, blower, pyro chiller) to support system operation.

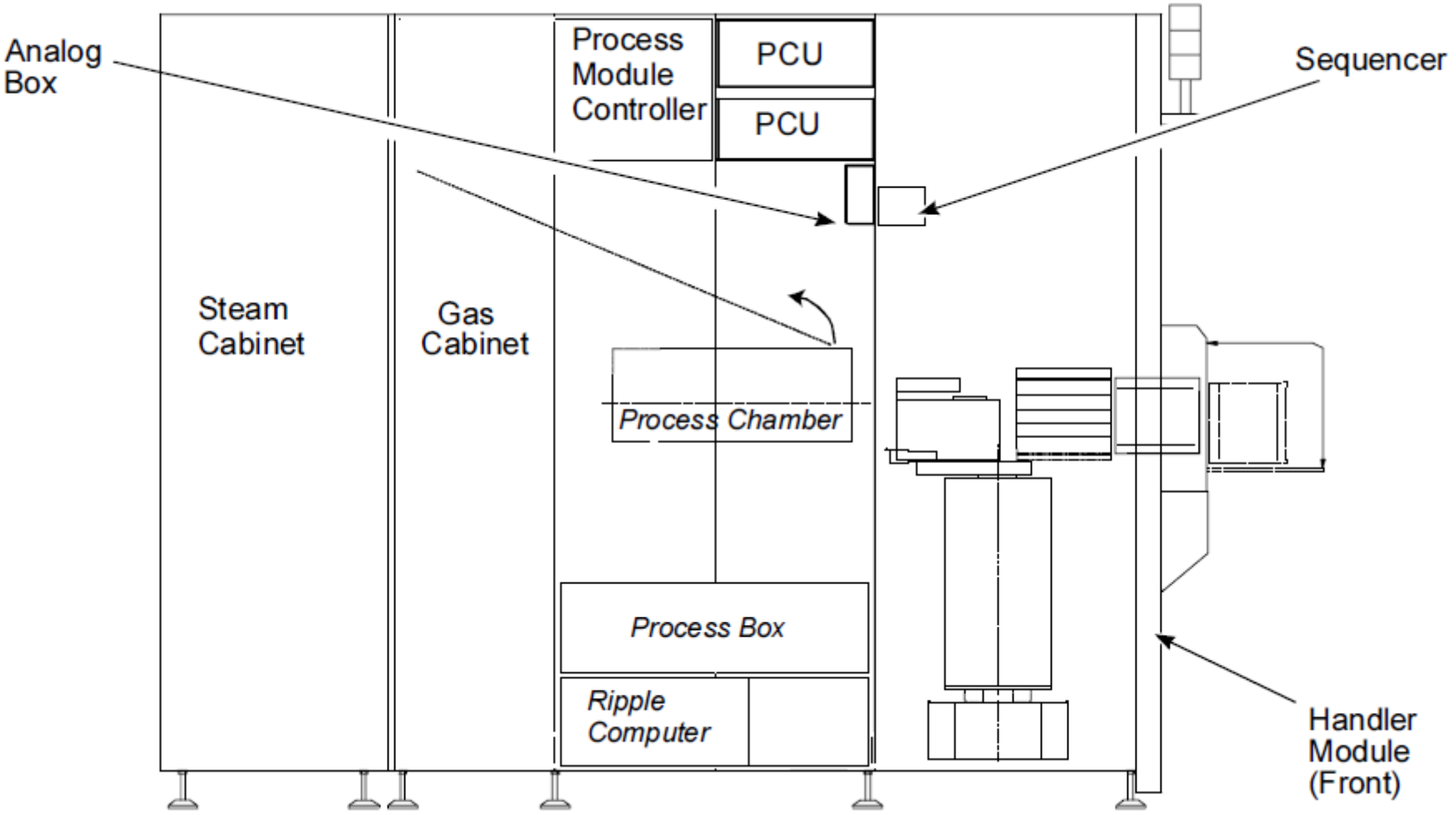


System Overview



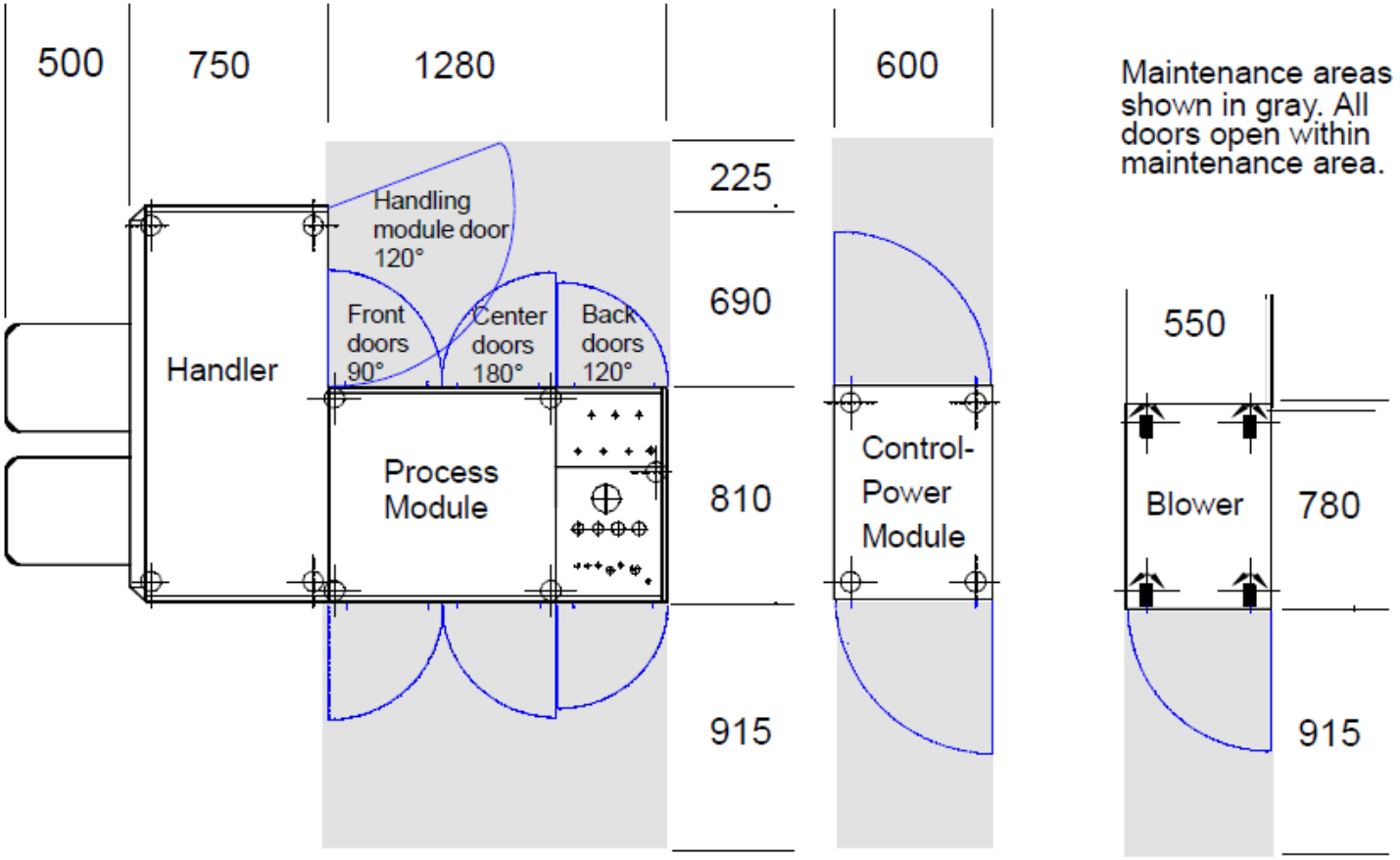
Process module component locations, right-side view

System Overview



Process module component locations, left-side view

System Overview



Footprint (including maintenance space): 4.19m2

Power-Control Module: 1.04m2 (may be sub-floor)

Blower: 0.93m2 (may be sub-floor)

All dimensions in mm.

Process Chamber Overview

